

PALM INTRANET

Day : Tuesday Date: 5/6/2008 Time: 17:57:00

Inventor Name Search Result

Your Search was:

Last Name = HONDA

First Name = TOSHIFUMI

\pplication#	Patent#	Status	Date Filed	Title	Inventor Name
08967013	6333992	150	11/10/1997	DEFECT JUDGEMENT PROCESSING METHOD AND APPARATUS	HONDA. TOSHIFUMI
08968125	6249598	150	::	SOLDER TESTING APPARATUS	HONDA, TOSHIFUMI
09413468	6622054	150	10/06/1999	METHOD MONITORING A QUALITY OF ELECTRONIC CIRCUITS AND ITS MANUFACTURING CONDITION AND SYSTEM FOR IT	HONDA, TOSHIFUMI
09661182	6553323	150	;	METHOD AND ITS APPARATUS FOR INSPECTING A SPECIMEN	HONDA, TOSHIFUMI
10081782	7181060	150	1	DEFECT INSPECTION METHOD	HONDA, TOSHIFUMI
10224087	6965429	150	08/19/2002	METHOD OF REVIEWING DETECTED DEFECTS	HONDA, TOSHIFUMI
10256585	6855930 V	150	09/27/2002	DEFECT INSPECTION APPARATUS AND DEFECT INSPECTION METHOD	HONDA, TOSHIFUMI
10378016	Not Issued	71		Method and its apparatus for classifying defects	HONDA, TOSHIFUMI
10640343	Not Issued	71	08/12/2003	Defect inspection method	HONDA, TOSHIFUMI
10762091	Not Issued	71	01/20/2004	Method of classifying defects	HONDA. TOSHIFUMI
10794267	Not Issued	3	03/04/2004	Defect classification method	HONDA, TOSHIFUMI
10809464	Not Issued	61	03/26/2004	Method and its apparatus for classifying defects	HONDA, TOSHIFUMI
10954421	Not Issued	71	10/01/2004	Method of observing defects	HONDA, TOSHIFUMI

11020255	7105815	150	12/27/2004	METHOD AND APPARATUS FOR COLLECTING DEFECT IMAGES	HONDA, TOSHIFUMI
11020265	7075077	150	12/27/2604	METHOD OF OBSERVING A SPECIMEN USING A SCANNING ELECTRON MICROSCOPE	HONDA, TOSHIFUMI
11042021	7305555	150	01/24/2005	DEFECT INSPECTION APPARATUS AND DEFECT INSPECTION METHOD	HONDA, TOSHIFUMI
11130121	7361896	150	05/17/2005	SCANNING ELECTRON MICROSCOPE AND A METHOD FOR ADJUSTING A FOCAL POINT OF AN ELECTRON BEAM OF SAID SCANNING ELECTRON MICROSCOPE	HONDA, TOSHIFUMI
11190829	Not Issued	30	07/28/2005	Method and its apparatus for classifying defects	HONDA, TOSHIFUMI
11248697	7170593	150	10/11/2005	METHOD OF REVIEWING DETECTED DEFECTS	HONDA, TOSHIFUMI
11268568	Not Issued	41	11/08/2005	Scanning electron microscope and system for inspecting semiconductor device	HONDA, TOSHIFUMI
1131)254	Not Issaed	30		Method and apparatus for reviewing defects	HONDA, TOSHIFUMI
11319721	Not Issued	71	12/29/2005	Scanning electron microscope and method for detecting an image using the same	HONDA, TOSHIFUMI
11325552	Not Issued	30	01/05/2006	Method and apparatus for reviewing defects	HONDA, TOSHIFUMI
11415286	Not Issued	30	05/02/2006	Observing method and its apparatus using electron microscope	HONDA, TOSHIFUMI
11488636	Not Issued	30	07/19/2006	Method and apparatus for reviewing defects of semiconductor device	HONDA, TOSHIFUMI
11634963	Not Issued	30	12/07/2006	Method and apparatus of reviewing defects on a semiconductor device	HONDA. TOSHIFUMI
11668510	Nat Issaed	30	01/30/2007	METHOD AND APPARATUS FOR REVIEWING DEFECTS	HONDA, TOSHIFUMI
11677669	Not Issued	30	02/22/2007	METHOD AND APPARATUS FOR DISPLAYING DETECTED DEFECTS	HONDA, TOSHIFUMI

11764228	Not Issaed	51	02/09/2007	Method and apparatus for reviewing defects by detecting images having voltage contrast	HONDA, TOSHIFUMI
11704350	Not Issued	30	(Method and apparatus for reviewing defects	HONDA. TOSHIFUMI
11747253	Not Issued	25	05/11/2007	SEM-TYPE REVIEWING APPARATUS AND A METHOD FOR REVIEWING DEFECTS USING THE SAME	HONDA. TOSHIFUMI
13779937	Not Issued	30	07/19/2007	REVIEWING APPARATUS USING A SEM AND METHOD FOR REVIEWING DEFECTS OR DETECTING DEFECTS USING THE REVIEWING APPARATUS	HONDA, TOSHIFUMI
12033470	Not Issued	19	01/01/0001	DEFECT REVIEW METHOD AND DEVICE FOR SEMICONDUCTOR DEVICE	HONDA, TOSHIFUMI

Inventor Search Completed: No Records to Display.

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Day : Teesday Date: 5/6/2008 Time: 17:57:20

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Your Search was:

Last Name = OKUDA First Name = HIROHITO

.pplication#	Patent#	Status	Date Filed	Title	Inventor Name
09413468	6622054	150	10/06/1999	METHOD MONITORING A QUALITY OF ELECTRONIC CIRCUITS AND ITS MANUFACTURING CONDITION AND SYSTEM FOR IT	OKUDA, HIROHITO
10050519	7231079	150	01/18/2002	METHOD AND SYSTEM FOR INSPECTING ELECTRONIC CIRCUIT PATTERN	OKUDA, HIROHITO
10081782	7181060	150	•	DEFECT INSPECTION METHOD	OKUDA, HIROHITO
10224087	6965429	150		METHOD OF REVIEWING DETECTED DEFECTS	OKUDA, HIROHITO
10256585	6855930 /	150	09/27/2002	DEFECT INSPECTION APPARATUS AND DEFECT INSPECTION METHOD	OKUDA, HIROHITO
10378016	Not Issued	71		Method and its apparatus for classifying defects	OKUDA. HIROHITO
10640343 V	Not Issued	71	08/12/2003	Defect inspection method	OKUDA, HIROHITO
10762091	Not Issued	71	01/20/2004	Method of classifying defects	OKUDA, HIROHITO
10794267	Not Issued	41	03/04/2004	Defect classification method	OKUDA, HIROHITO
10809464	Not Issued	61	03/26/2004	Method and its apparatus for classifying defects	OKUDA, HIROHITO
10918340	7034299	150		TRANSMISSION ELECTRON MICROSCOPE SYSTEM AND METHOD OF INSPECTING A SPECIMEN USING THE SAME	OKUDA, HIROHITO
11020265	7075077	150	12/27/2004	METHOD OF OBSERVING A SPECIMEN USING A	OKUDA, HIROHITO

				SCANNING ELECTRON MICROSCOPE	
13042021	7205558	150	:	DEFECT INSPECTION APPARATUS AND DEFECT INSPECTION METHOD	OKUDA. HIROHITO
11248697	7170593	150	10/11/2005	METHOD OF REVIEWING DETECTED DEFECTS	OKUDA, HIROHITO
11478615	Not Issued	30		Apparatus and method for electron beam inspection with projection electron microscopy	OKUDA, HIROHITO
11488734	Not Issued	30	07/19/2006	Method and apparatus for inspecting defects of circuit patterns	OKUDA, HIROHITO
13601723	Not Tasued	30		Method and apparatus for inspecting pattern defects and mirror electron projection Type or multi-beam scanning type electron beam apparatus	OKUDA. HIROHITO

Inventor Search Completed: No Records to Display.

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OKUDA	(HIROHITO	Search

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